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|-----------------------------|---------------------------------------|--------------|------------------------|---|

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\*\* CONTINUING DATA \*\*\*\*\* *Verified*  
 This application is a CIP of 10/278,992 10/24/2002  
 which is a DIV of 09/686,624 10/12/2000 PAT 6,706,646

\*\* FOREIGN APPLICATIONS \*\*\*\*\* *Verified*  
 REPUBLIC OF KOREA 2003-10159 02/18/2003  
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IF REQUIRED, FOREIGN FILING LICENSE GRANTED  
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|--|---|---|------------------------|-----------------------|----------------------------|
| Foreign Priority claimed<br>35 USC 119 (a-d) conditions met<br>Verified and Acknowledged | <input checked="" type="checkbox"/> yes <input type="checkbox"/> no<br><input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after Allowance<br><i>[Signature]</i><br>Examiner's Signature | STATE OR<br>COUNTRY<br>KOREA,<br>REPUBLIC<br>OF | SHEETS<br>DRAWING<br>8 | TOTAL<br>CLAIMS<br>25 | INDEPENDENT<br>CLAIMS<br>2 |
|--|---|---|------------------------|-----------------------|----------------------------|

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TITLE  
 Method of forming a silicon oxide layer in a semiconductor manufacturing process

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